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Brian A. VaartstraPriority FILING DATE  
March 14, 2002Priority GROUP  
1765

## U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>h</i>	AA	5,908,947	06/1999	Vaartstra			
	AB	6,287,965	09/2001	Kang et al			
<i>X</i>	AC	6,391,803	05/2002	Kim et al			
<i>X</i>	AD	5,840,897	11/1998	Kirlin et al			
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
<i>A</i>	AM	2002027063	04/2002	PCT/Gordon et al				
	AN							
	AO							
	AP							
	AQ							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

<i>h</i>	AR		Sean T. Barry, et al, "Monomeric Chelated Amides of Aluminum and Gallium: Volatile, Miscible Liquid Precursors for CVD", Harvard University Chemical Laboratories, Mater. Res. Soc. Symp. Proc., 2000, Vol. 606, pg. 83
<i>h</i>	AS		Kim et al., "Compositional Variations of TiAlN Films Deposited by Metalorganic Atomic Layer Desposition Method", Jpn. J. Applied Physics, vol. 41, part 1 (2a) 2-2002, pages 562-565.
	AT		

EXAMINER

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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.